

Stage:

- ISO DN 350 CF Flange
- Mover size 120 mm x 120 mm
- Moving area 240 mm x 240 mm

Fields of use:

- Lithography reticles (EUV, DUV)
- Semiconductor layering (Wafer)
- Nano layering
- AFM (Atomic Force Microscopy)
- SIMS (Secondary Ion Mass Spectrometry)
- FIB (Fused Ion Beam)
- SHIM (Scanning Helium Ion Microscopy)

Content:

- Mover
- ISO-flange with drive unit
- Control unit including cable
- Manual

Technical data:

- Vacuum level: 1·10e-9 mbar
- Repeatability: +/- 1 µm
- Accuracy: +/- 1 µm
- Rotation (Z): +/- 15°
- Payload: 600 g
- Max. temperature: 120 °C
- Power supply: 48 V DC



Product advantages:

- No feedthrough necessary
- No particles
- No wear
- No outgassing
- High accuracy
- Mounting via standard flange
- Metallic sealable

